



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **IBARA, Yoshikazu et al.**

Group Art Unit: **2823**

Serial No.: **09/892,893**

Examiner: **COLEMAN, William D.**

Filed: **June 28, 2001**

P.T.O. Confirmation No.: **1585**

For: **METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICES**

47/A  
12/21/w  
ydm.

**AMENDMENT UNDER 37 CFR § 1.111**

Commissioner for Patents  
Washington, D.C. 20231

December 2, 2002

Sir:

In response to the Office Action dated August 1, 2002, the period for response therefor extended by a Petition for a One-Month Extension of Time, please amend the above-identified application as follows:

**IN THE TITLE:**

Amend the title as follows:

METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICES WITH SILICIDE FILMS THEREON

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DEC - 5 2002  
TECHNOLOGY CENTER 2800